

FORM PTO-1449

U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICE

ATTORNEY DOCKET NO. 001945 USA P02/ETCH/SILICON/JB

SERIAL NO
09/362,924

LIST OF ART CITED BY APPLICANT

(Use several sheets if necessary)

APPLICANT Chow, et al

FILING DATE: 07/27/99

GROUP 1746

U.S. PATENT DOCUMENTS

Examiner Initial	DOCKET NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
<i>Joe</i>	5 7 4 1 3 9 6	04/21/98	Loewenstein			
<i>Joe</i>	5 6 5 1 8 5 6	07/29/97	Keller, et al			
	AC					
	AD					
	AE					
	AF					
	AG					
	AH					
	AI					

FOREIGN PATENT DOCUMENTS

	DOCKET NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO
<i>Joe</i>	0 8 3 7 4 9 7	04/22/98	EP				
<i>Joe</i>	0 2 0 0 9 5 1	04/11/86	EP				
	AL						
	AM						
	AN						

OTHER ART (Including Author, Title, Date, Pertinent Pages, etc.)

<i>Joe</i>	AO	PCT Report dated 06/22/01, European Patent Office, P.B. 5818 Patentlaan 2 NL-2280 HV Rijswijk
<i>Joe</i>	AP	Zaleski, et al "Tungsten Silicide/Polysilicon Stack Etching using Mixed Fluorine Chlorine Chemistry in a High Density Plasma Chamber", Electrochemical Society Proceedings Volume 98-4, pages 203-209.
<i>Joe</i>	AQ	

EXAMINER

DATE CONSIDERED 7/31/01

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.